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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Wunnicke, et al. Docket No.: INF-138
 Serial No.: 10/781,920 Art Unit: 1756
 Filed: February 20, 2004 Examiner: TBD
 For: Method for Fabricating a Resist Mask for Patterning Semiconductor Substrates

Commissioner for Patents
 P.O. Box 1450
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Associate Power of Attorney

Dear Sir:

I hereby appoint as associate attorneys of record all attorneys at customer number 25962.

Also, please direct all future correspondence to:

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Respectfully submitted,

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